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Docket Number: PD-02-0744

Applicant Robert M'Closkey et al.

Date Mailed: May 28, 2004

ENFORMATION DISCLOSURE STATEMENT

Form 1449\*

Sheet 1 of 2

Application Number: 10/603,557

Group Art Unit 2816 28 IN AN APPLICATION Filing Date: June 25, 2003 . Juh 0 2 2005 U.S. PATENT DOCUMENTS FILING DATE IF SUBCLASS CLASS NAME DATE ÉAMINER DOCUMENT NO. **APPROPRIATE** INITIAL 8/14/03 Challoner et al. 2003/0150267 11/13/1888 Watrous 392,650 04/20/93 Bernstein 5,203, 208 07/13/93 Vamham et al. 5,226,321 07/08/97 Okada 5,646,346 Kobayashi et al. 09/09/97 5,665,915 Lee et al. 5,783,749 07/21/98 04/13/99 Tang et al. 5,894,090 Kubena et al. 05/18/99 5,905,202 07/06/99 Pinson 5,920,012 01/04/00 Ljung 6,009,751 04/04/00 Neukermans et al. 6.044,705 Cargille 12/26/00 6,164,134 Fell et al. 09/04/01 6,282,958 Challoner et al. 6,289,733 B1 09/18/01 04//09/02 Gutierrez et al. 6,367,786 Wine et al. 02/04/03 6,515,278 10/07/03 Challoner 6.629.460 FOREIGN PATENTS TRANSLATION **CLASS** SUBCLASS COUNTRY DOCUMENT NO. DATE YES NO WO 96/38710 12/05/96 PCT PCT 04/16/98 WO 98/15799 05/30/96 Germany DE 44 42 033 A1 NON-PATENT DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.) N. Barbour et al., "Micromechanical Silicon Instrument and Systems
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EXAMINER: Initial if reference considered, whether of not citation is in conformance with MPEP 609; draw line through citation in conformance and not considered. Include copy of this form for next communication to the Applicant.

\*Substitute Disclosure Statement Form (PTO-1449)

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INFORMATION DISCLOSURE STATEMENT	Applicant: Robert M'Closkey et al.	
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